

Conclusion

The foregoing amendments are being made to place the application in condition for examination. A favorable action on the merits is respectfully solicited.

Attached hereto is a marked-up version of the changes made to the specification and claims by the current amendment. The attachment is captioned "Version with markings to show changes made."

If there are any other fees due in connection with the filing of this paper, please charge the fees to our Deposit Account No. 50-0310. If a fee is required for an extension of time under 37 C.F.R. § 1.136 not accounted for above, such an extension is requested and the fee should also be charged to our Deposit Account.

Respectfully Submitted,

By:



Robert J. Goodell
Reg. No. 41,040

Dated: December 7, 2001

Customer Number 009629
MORGAN, LEWIS & BOCKIUS LLP
1800 M Street, N.W.
Washington, DC 20036
202-467-7549 (Phone)
202-467-7258 (Fax)

VERSION WITH MARKINGS TO SHOW CHANGES MADE

Claim 1 has been amended as follows:

1.(Amended) A method of manufacturing a flash memory device, comprising the steps of:

sequentially forming a tunnel oxide film and a first polysilicon film on a semiconductor substrate;

~~{and then}~~ etching ~~{said}~~ the first polysilicon film and a ~~{given}~~ first portion region of ~~{said}~~ the tunnel oxide film;

forming a lower oxide film on the ~~{entire structure}~~ semiconductor substrate;

performing a nitrification process to form a nitrogen layer below ~~{said}~~ the lower oxide film;

performing an annealing process using an oxygen gas so that ~~{said}~~ the nitrogen layer is ~~{moved on the}~~ transferred to a surface of ~~{said}~~ the lower oxide film, thus forming a nitride film;

forming ~~{a}~~ an upper oxide film on the ~~{entire surface}~~ semiconductor substrate to form a dielectric film ~~{consisting of said}~~ including the lower oxide film, ~~{said}~~ the nitride film, and ~~{said}~~ the upper oxide film;

sequentially forming a second polysilicon film, a tungsten silicide film, and an anti-reflection film on the ~~{entire structure}~~ semiconductor substrate;

patterning ~~{said}~~ the anti-reflection film, ~~{said}~~ the tungsten silicide film, ~~{said}~~ the second polysilicon film, and ~~{said}~~ the dielectric film to form a control gate₁ and ~~{then}~~ patterning ~~{said}~~ the first polysilicon film and ~~{said}~~ the tunnel oxide film to form a floating gate.

Claim 2 has been amended as follows:

2.(Amended) The method ~~{of manufacturing a flash memory device}~~ according to claim 1, wherein ~~{said}~~ the lower oxide film is formed using DCS gas and one of N₂O ~~{or}~~ and NO gas at ~~{the}~~ a temperature of ~~[810—850]~~ 810-850°C.

Claim 3 has been amended as follows:

3.(Amended) The method ~~{of manufacturing a flash memory device}~~ according to claim 1, wherein ~~{said}~~ the lower oxide film is formed ~~{in}~~ to a thickness of ~~[35—100]~~ 35-100Å at ~~{the}~~ a deposition rate of ~~[4—10]~~ 4-10Å/min.

Claim 4 has been amended as follows:

4.(Amended) The method ~~{of manufacturing a flash memory device}~~ according to claim 1, wherein ~~{said}~~ the nitrification process is performed by introducing one of N₂O ~~{or}~~ and NO of ~~[1—20]~~ 1-20 into ~~{the}~~ a furnace at ~~{the}~~ a temperature of ~~[810—850]~~ 810-850°C for ~~[10—20]~~ 10-20 minutes, thus forming a nitrogen layer of ~~[3—5]~~ 3-5Å in thickness in ~~{said}~~ the lower oxide film.

Claim 5 has been amended as follows:

5.(Amended) The method ~~{of manufacturing a flash memory device}~~ according to claim 1, wherein ~~{said}~~ the annealing process using ~~{the}~~ an oxygen gas is performed by introducing ~~{an}~~ the oxygen gas of ~~{5-20}~~ 5-20 into ~~{the}~~ a furnace at ~~{the}~~ a temperature of ~~{850-950}~~ 850-950°C for ~~{5-20}~~ 5-20 minutes.

Claim 6 has been amended as follows:

6.(Amended) The method ~~{of manufacturing a flash memory device}~~ according to claim 1, wherein ~~{said}~~ the upper oxide film is formed using DCS gas and one of N₂O ~~{or}~~ and NO gas at ~~{the}~~ a temperature of ~~{810-850}~~ 810-850°C.

Claim 7 has been amended as follows:

7.(Amended) The method ~~{of manufacturing a flash memory device}~~ according to claim 1, wherein ~~{said}~~ the upper oxide film is formed ~~{in}~~ to a thickness of ~~{35-100}~~ 35-100Å at ~~{the}~~ a deposition rate of ~~{4-10}~~ 4-10Å/min.

Claim 8 has been amended as follows:

8.(Amended) The method ~~{of manufacturing a flash memory device}~~ according to claim 1, wherein ~~{said}~~ the second polysilicon film is formed in a double structure of a doped polysilicon film and an undoped polysilicon film.

9.(Amended) The method ~~[of manufacturing a flash memory device]~~ according to claim 8, wherein ~~[said]~~ the polysilicon film and ~~[said]~~ the undoped polysilicon film ~~[is]~~ are deposited at ~~[the]~~ a ratio of ~~[4:1-7:1]~~ 4:1-7:1.